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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9257**  
Tetsuji TOGAWA et al. : Attorney Docket No. 2005\_0993A  
Serial No. 10/539,245 : Group Art Unit 3723  
Filed March 29, 2006 : Examiner Maurina T. Rachuba  
SUBSTRATE HOLDING MECHANISM, : **Mail Stop AMENDMENT**  
SUBSTRATE POLISHING APPARATUS  
AND SUBSTRATE POLISHING METHOD

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**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action mailed April 11, 2007, please amend the above-identified application as follows: